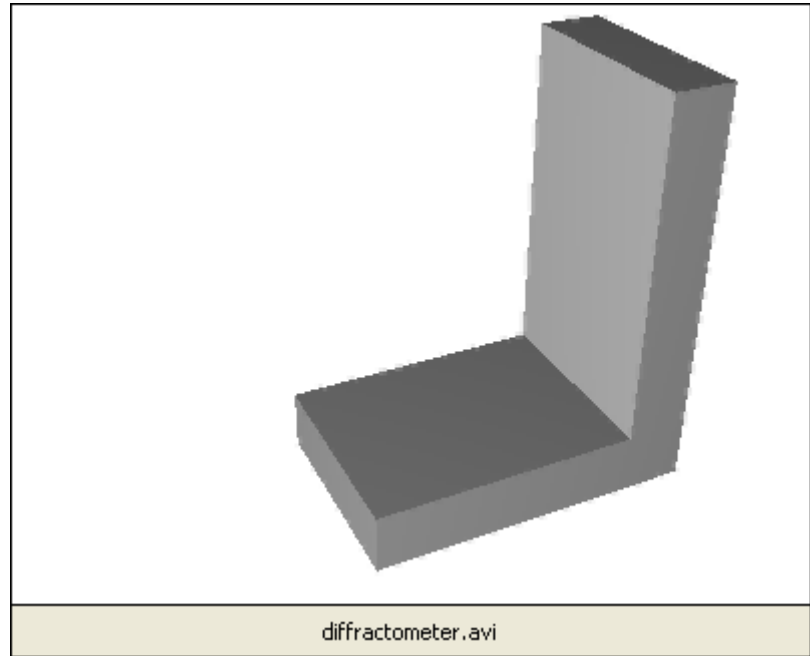


Experimental part

1) The diffractometer

Has many **degrees of freedom** with high accuracy (0.001° angular resolution / 0.01mm translational resolution).

Many **slits** are necessary to **define the beam direction** (not discussed here).



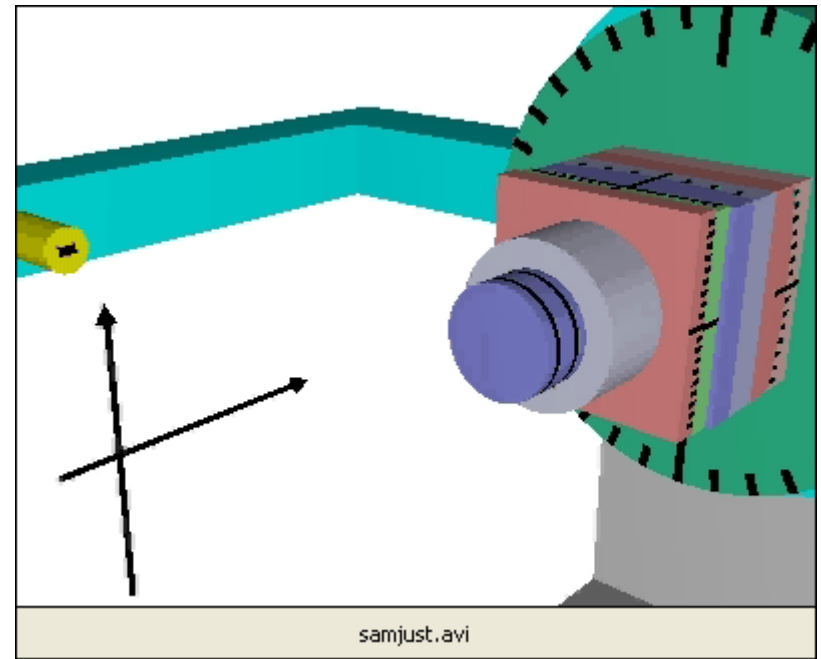
Degrees of freedom

- 2θ : Detector rotation
- ω : Sample rotation (incident angle)
- χ : 1. Euler angle (align surface parallel)
- ϕ : 2. Euler angle (not used for reflectivity)
- y : Sample movement up↔down
- x : Sample movement along the beam
- z : Sample movement horizontally
- gy : Goniometer movement up↔down

2) Alignment of the sample

Goal

Put the center of the sample surface to center of rotation (marked by the beam after centering the diffractometer).



Procedure

- 1) Scan the primary beam without the sample. Note the intensity I_0 and the width σ and go with 2θ to the maximum. Calibrate this to 0.
- 2) Scan the sample in y -direction. Move y so that the sample cuts half of the beam.
- 3) Scan ω . Find the maximum, go there and calibrate to 0.
- 4) Redo step 2).
- 5) The ω -scan may not look symmetric. Move the sample in x -direction until it is.
- 6) Go to some $\omega-2\theta$ value (e.g. $\omega=1^\circ$, $2\theta=2^\circ$), scan ω and go to the maximum. Calibrate this as $2\theta/2$. This is much more accurate than step 3).
- 7) If the width of 6) is **not** $\sigma/2$ the sample is bent and has to be cut in smaller pieces!
- 8) Scan χ widely and go to the maximum to make the surface parallel to the beam.

Techniques for refinement

1) Standard technique

- Take the data and have a qualitative look at it.
- Parametrize a density profile by film thickness, averaged film densities and interface roughnesses which may match the data. So create a model of the system.
- Take into account all external parameters (resolution of the diffractometer, background, size of the beam, size of the sample) and include them into the model.
- Take a reasonable assumption on the parameters which may match the sample conditions best (preknowledge) and calculate a reflectivity using the Parratt formalism with modified Fresnel reflection coefficients.
- Optimize χ^2 under the constraint of physical reasonability.

$$\chi^2 = \sum_{j=1}^M \left(I_{j, \text{Data}}(q_z) - I_{j, \text{Model}}(q_z) \right)^2 \quad \text{with } M \text{ data points}$$

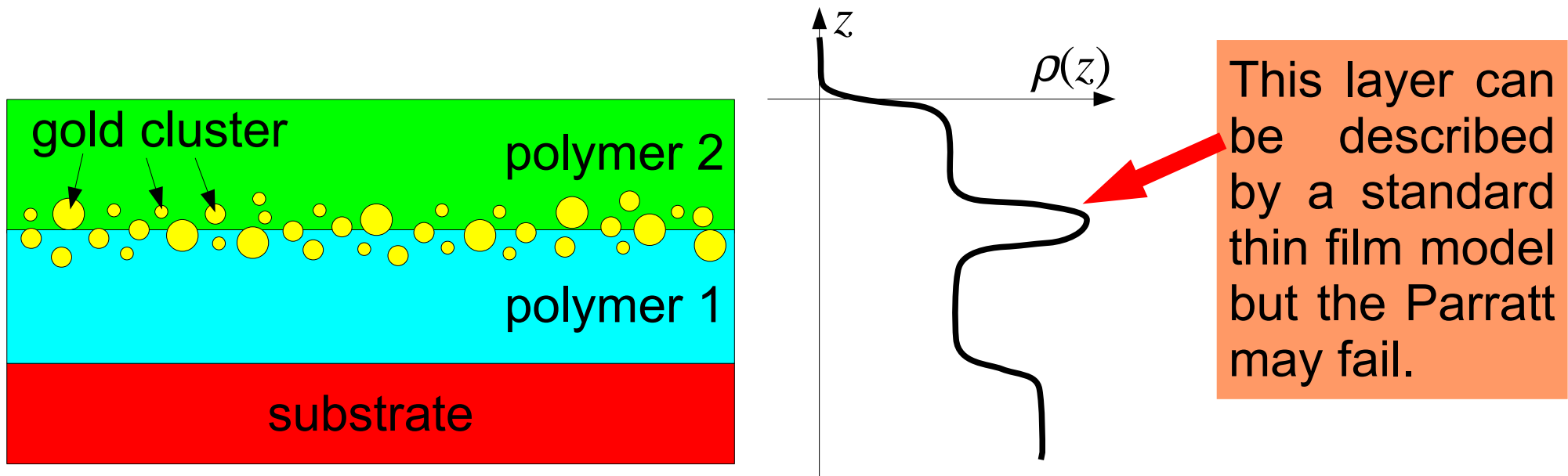
2) Effective density model

The standard technique **usually works well**.

It **fails** if the system contains **thin layers with roughnesses equal or larger than the film thickness** (incomplete layers).

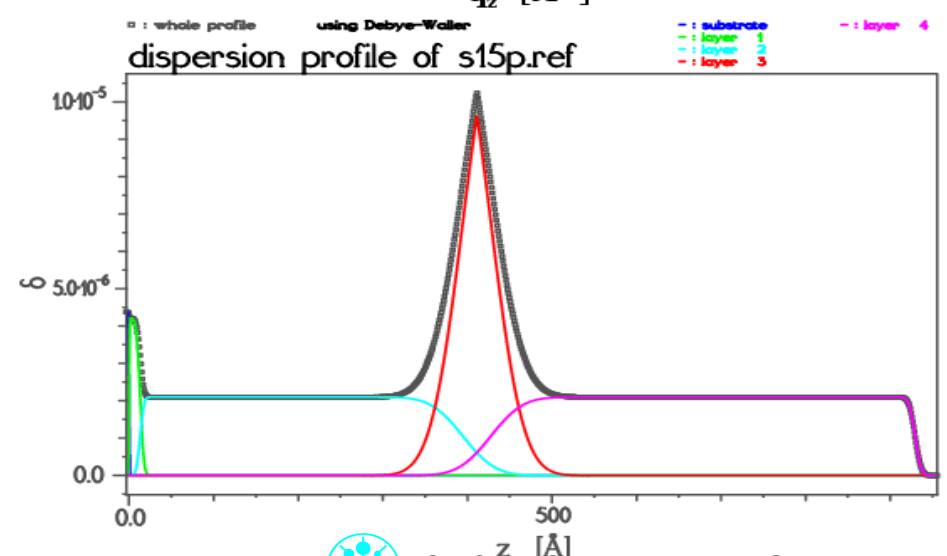
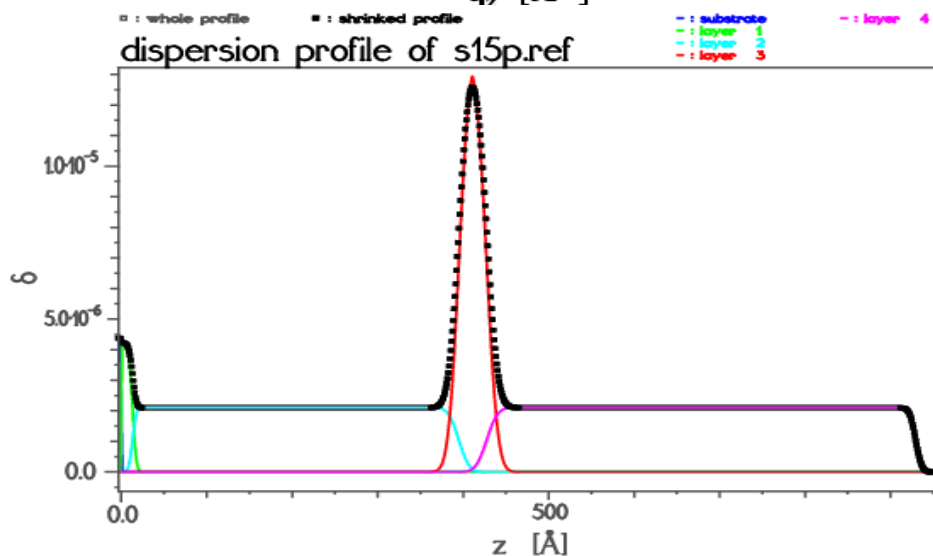
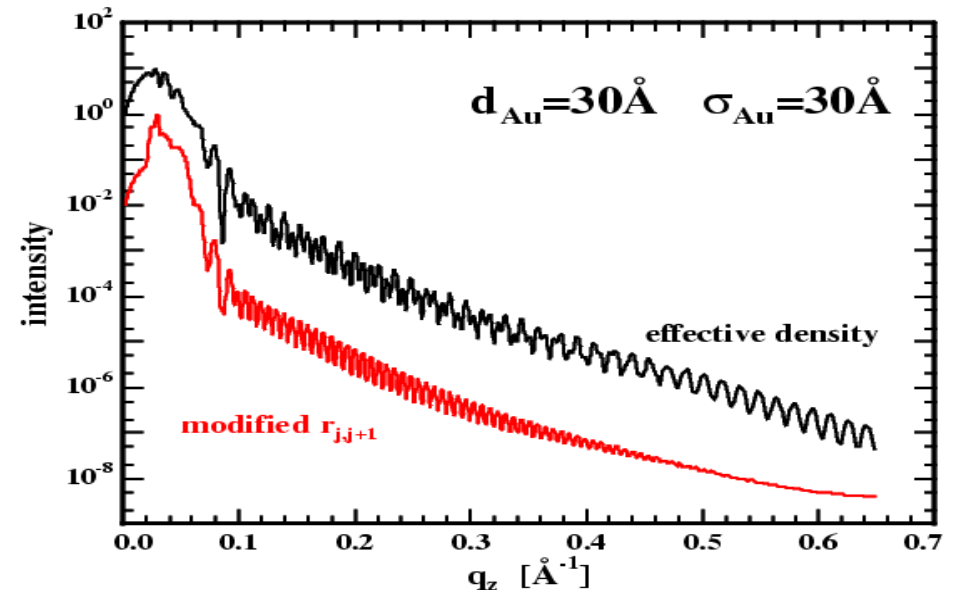
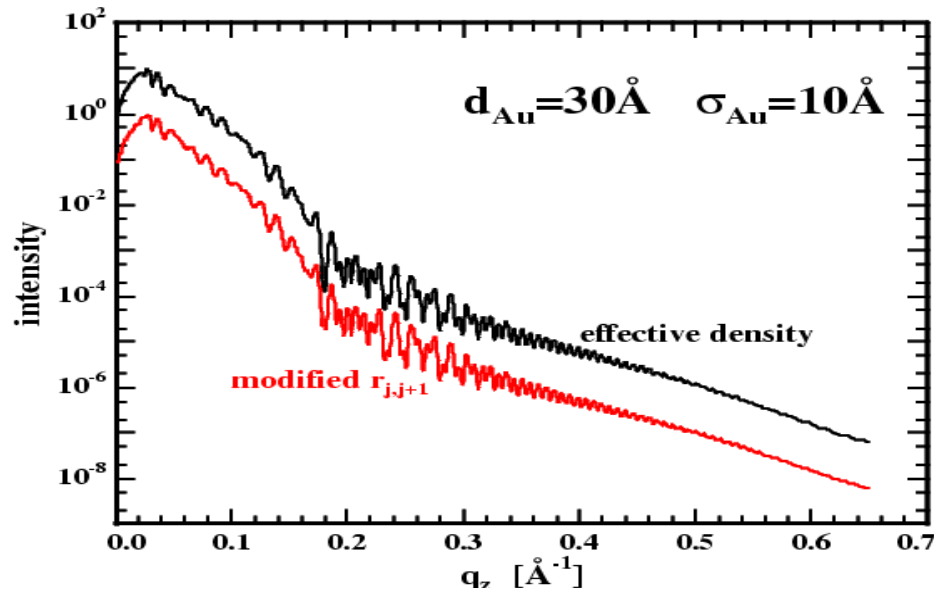
Reason: Interfaces cannot be treated separately any more.

Example: Thin (30Å) gold layers embedded in polymer matrices

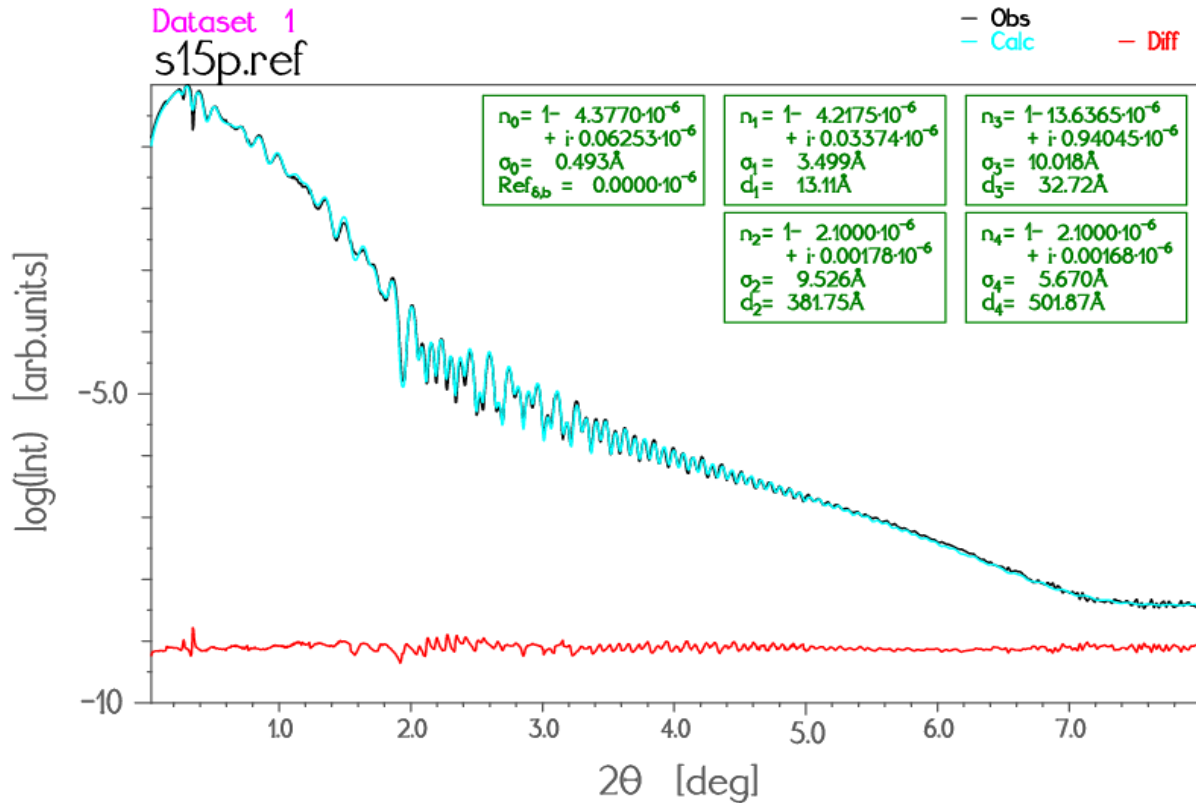
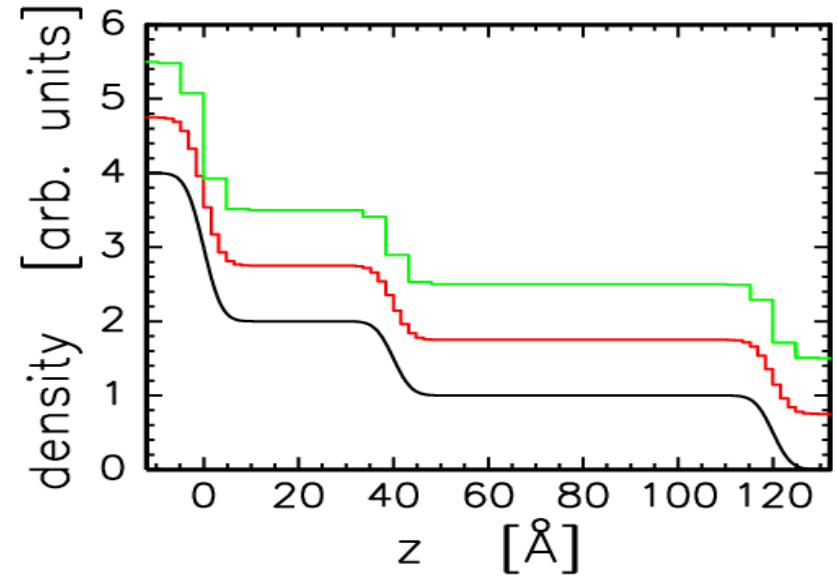
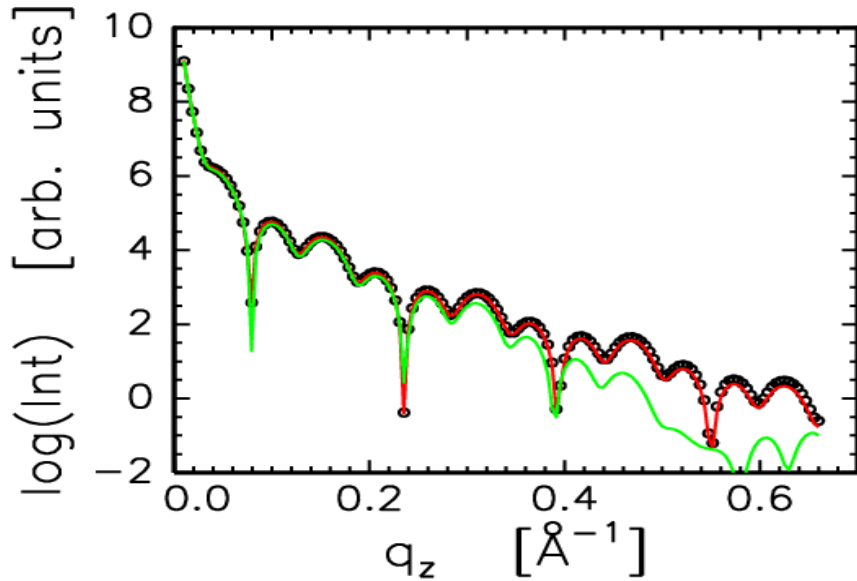


Reflectivity can be calculated by the effective density model.

- 1) calculating the whole density profile first
- 2) slicing into many very thin completely smooth sublayers
- 3) using this slicing for the iterative Parratt algorithm (slow!)



The slicing has to be **adapted** to the q_z -range which has been covered.



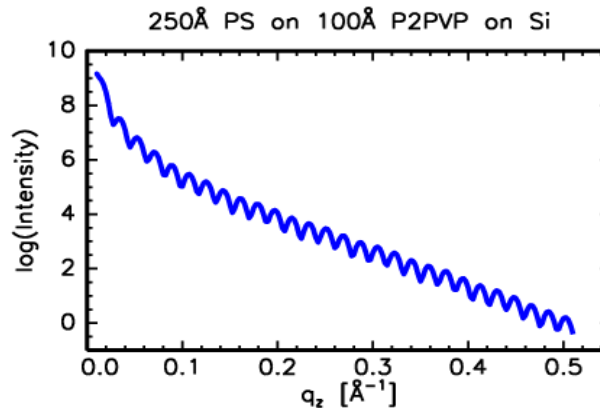
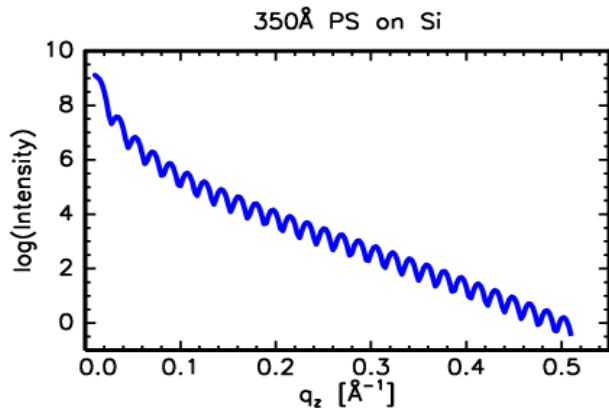
Data and fit of a
Si-PSSA(15%)-Au-PS
thin film system
(effective density model)

red curve is the difference

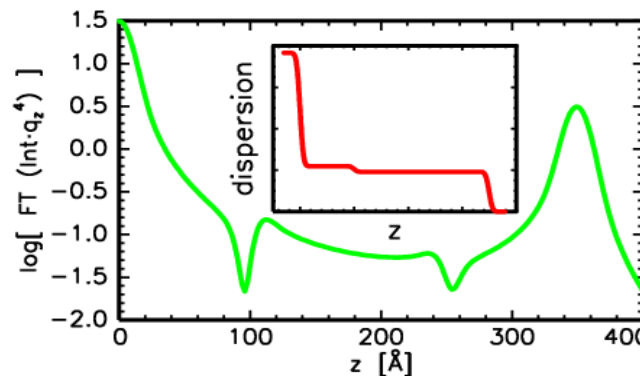
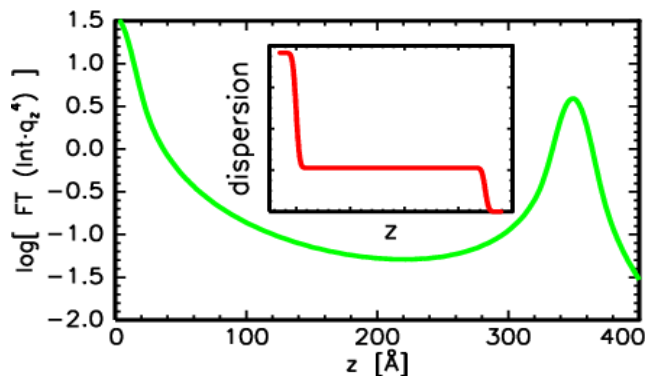
3) The Fourier method

To **increase** the sensitivity to **low contrast** interfaces: Include the Fourier backtransformation of $I(q_z)$ (**Patterson function** $P(z)$) to the refinement.

$$P(z) = \left| \int_{q_{z,low}}^{\infty} q_z^4 I(q_z) \cos(q_z z) dq_z \right|^2 \quad \Rightarrow \quad I(q_z) \propto \frac{1}{q_z^4} \left| \int \frac{d\rho(z)}{dz} \exp(iq_z z) dz \right|^2$$



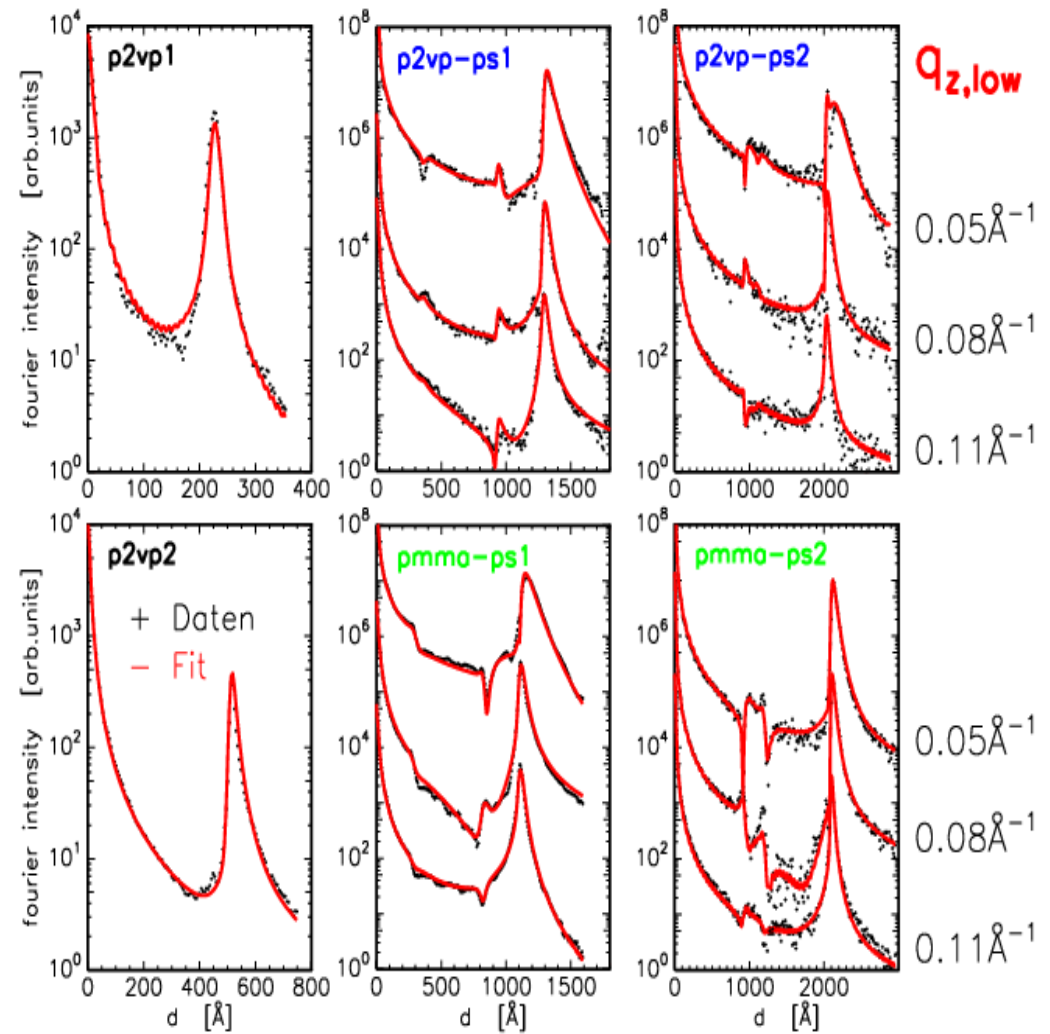
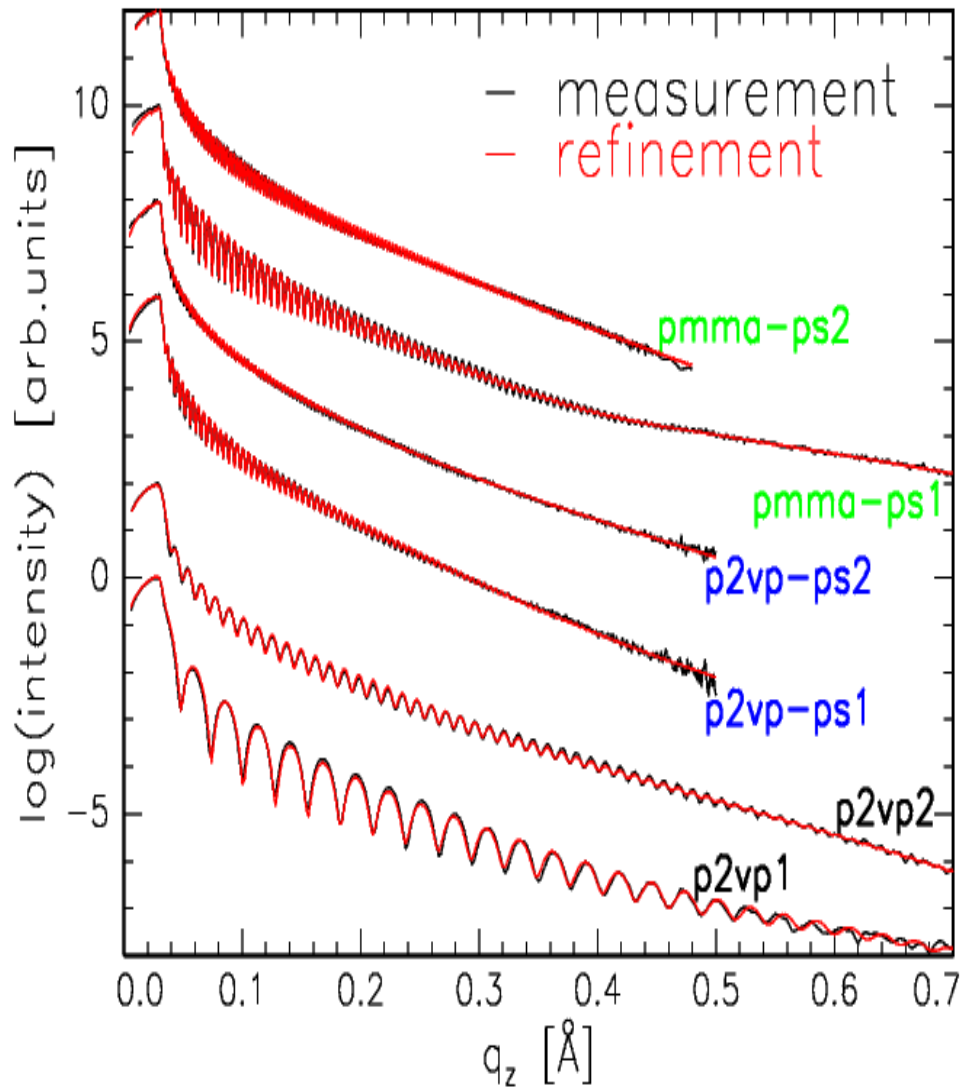
Position of the peaks/dips
 \Rightarrow
 Layer thickness



Shape+intensity
 \Rightarrow
 Probability function of the interface

Polymer Mono- and Bilayers @ 11keV

$$\delta_{\text{Si}} = 4.03 \cdot 10^{-6} / \delta_{\text{PS}} = 1.92 \cdot 10^{-6} / \delta_{\text{P2VPP}} = 2.00 \cdot 10^{-6} / \delta_{\text{PMMA}} = 2.17 \cdot 10^{-6}$$



Summary

- X-ray or neutron reflectometry is a very helpful tool to investigate thin layer systems.
- The reflectivity is basically sensitive to the density profile perpendicular to the sample surface.

$$I(q_z) \propto \frac{1}{q_z^4} \left| \int \frac{d\rho}{dz} \exp(iq_z z) dz \right|^2$$

- Special care has to be taken when aligning the samples on a diffractometer.
- To successfully analyze the data often special tricks have to be applied.